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PROCESSING CHAMBERS****Publication Classification**(51) **Int. Cl.**
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(2013.01); *H05B 2203/008* (2013.01)(71) Applicant: **Applied Materials, Inc.**, Santa Clara,
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HOWELLS, Portland, OR (US)(21) Appl. No.: **17/729,715**(22) Filed: **Apr. 26, 2022****Related U.S. Application Data**(60) Provisional application No. 63/181,626, filed on Apr.
29, 2021.**ABSTRACT**

A window assembly for a thermal processing chamber applicable for thermal processing of a semiconductor substrate is provided. The window assembly includes an upper window, a lower window, and a plurality of linear reflectors disposed between the upper window and the lower window. The plurality of linear reflectors extend lengthwise parallel to each other and parallel to a plane of the window assembly. The window assembly includes a pressure control region defined between the upper window, the lower window, and side surfaces of each linear reflector.

